



MICRON.140DV1C1

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Weimin Li et al.
Appl. No.	:	10/757,638
Filed	:	January 13, 2004
For	:	TECHNIQUE FOR HIGH EFFICIENCY METALORGANIC CHEMICAL VAPOR DEPOSITION
Examiner	:	Michael K. Luhrs
Group Art Unit	:	2824

AMENDMENT AFTER FINAL

Mail Stop AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The Applicant respectfully submits the following amendments and remarks in response to the Office Action mailed December 13, 2004.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.